

#4

Sheet 1 of 1

FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE					ATTY. DOCKET NO. ONX-105		SERIAL NO. Not assigned	
LIST OF PRIOR ART CITED BY APPLICANT (Use several sheets if necessary)					APPLICANT Behrang Behin			
					FILING DATE Filed herewith		GROUP Not assigned	

J-925 U.S. PTO
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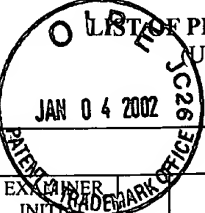
U.S. PATENT DOCUMENTS													
EXAMINER INITIAL		DOCUMENT NUMBER							DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
ON	A	5	6	4	8	6	1	8	7/15/97	Neukermans et al.	73	862.08	1/31/96
ON	B	5	9	9	8	9	0	6	12/7/99	Jerman et al.	310	309	8/17/98
ON	C	5	9	6	9	8	4	8	10/19/99	Lee et al.	359	298	7/3/97
ON	D	5	8	8	1	1	9	8	3/9/99	Haake	385	136	2/10/97
ON	E	5	9	9	5	3	3	4	11/30/99	Fan et al.	360	106	12/30/97
	F												
	G												
	H												

FOREIGN PATENT DOCUMENTS															
		DOCUMENT NUMBER							DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION		
														YES	NO
	I														
	J														

OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)		
ON	K	"A Flat High-Frequency Scanning Micromirror" ; Robert A. Conant, Jocelyn T. Nee, Kam Y. Lau and Richard S. Muller; Berkeley Sensor & Actuator Center, University of California, Berkeley
	L	
	M	
	N	

EXAMINER <i>John Foja</i>	DATE CONSIDERED <i>10/7/03</i>
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* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE										AGENT DOCKET NO. ONX-105		SERIAL NO. 09/751,660	
<div style="text-align: center;">  <p>LIST OF PRIOR ART CITED BY APPLICANT (Use several sheets if necessary)</p> </div>										APPLICANT Behrang Behin et al.			
										FILING DATE 12/28/2000			
U.S. PATENT DOCUMENTS													
EXAMINER INITIAL	CLASS	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE						
<i>OR</i>	A	5 7 2 3 3 5 3	3/3/1998	Muenzel et al.	437	51	2/12/1996						
<i>OR</i>	B	5 7 2 6 0 7 3	3/10/1998	Zhang et al.	437	228	1/16/1996						
<i>OR</i>	C	5 7 5 3 9 1 1	5/19/1998	Yasuda et al.	250	306	1/16/1997						
<i>OR</i>	D	5 8 7 2 8 8 0	2/16/1999	Maynard	385	88	8/12/1996						
<i>BYR</i>	E	6 3 3 0 1 0 2	12/11/2001	Daneman et al.	359	290	3/25/2000						
FOREIGN PATENT DOCUMENTS													
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION						
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<i>OR</i>	F	0 9 0 7 0 7 6 A 2	4/7/1999	Europe	G01N	27/00							
<i>OR</i>	G	0 9 0 7 0 7 6 A 3	10/4/2000	Europe	H01J	37/63							
<i>OR</i>	H	0 9 1 1 9 5 2 A 2	4/28/1999	Europe	H02N	1/00							
<i>OR</i>	I	0 9 1 1 9 5 2 A 3	4/5/2000	Europe	H02N	1/00							
<i>OR</i>	J	1 9 7 5 7 1 8 1 A	7/1/1997	Germany	G02B	6/35		X					
<i>OR</i>	K	1 9 6 4 4 9 1 8 A	4/30/1998	Germany	G02B	6/35	X						
<i>OR</i>	L	2 9 6 1 1 8 8 1 8	12/12/1996	Germany	G02B	6/35		X					
<i>OR</i>	M	2 7 3 2 4 6 7 A 1	4/10/1996	France	G01P	15/08		X					
OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)													
<i>OR</i>	N	"Electrostatic Comb Drive For Vertical Actuation" A.P. Lee et al., Proceedings of the SPIE, SPIE, Bellingham, VA, vol. 3224, Sept 29, 1997, pp 109-119											
<i>OR</i>	O	"Design, Fabrication, Position Sensing, And Control Of An Electrostatically-Driven Polysilicon Microactuator," P. Cheung et al, IEEE Transactions on Magnetics, vol. 32, no. 1, 1 Jan. 1996, pp 122-128											
<i>OR</i>	P	"Optical Methods For Micromachine Monitoring And Feedback", F.M. Dickey et al., Sensors and Actuators, vol. 78, 1999, pp 220-235											
<i>OR</i>	Q	"A High Sensitivity Z-Axis Capacitive Silicon Microaccelerometer with a Torsional Suspension", Selvakumar et al., Journal of Microelectromechanical Systems, IEEE Inc., New York, vol. 7, No. 2, June 1998, pp 192-200											
<i>OR</i>	R	"MEMS Fabrication of High Aspect Ratio Track-Following Micro Actuator for Hard Disk Drive Using Silicon On Insulator", B. H. Kim et al., Technical Digest of the IEEE International MEMS '99 Conference. 12 th IEEE International Conference on Micro Electro Mechanical Systems. Orlando, FL, Jan 17-21, 1999, IEEE International Micro Electro Mechanical Systems Conference, New York, NY, 1999, pp 53-56.											
<i>OR</i>	S	"Fabrication of Comb-Shaped Microactuator for Multi-Degrees-of-Freedom System", F. Fujikawa et al., Robotics, CIM and Automation, Emerging Technologies, San Diego, Nov. 9-13, 1992, Proceedings of the International Conference on Industrial Electronics, Control, Instrumentation and Automation (IECON), New York, NY, IEEE, US, vol. 2 Conf 18, 9 November 1992, pp 990-995											
<i>OR</i>	T	"Integrated Micro-Scanning Tunneling Microscope", Xu et al., Applied Physics Letters, American Institute of Physics, New York, vol. 67, No. 16, October 16, 1995 pp 2305-2307.											
<i>OR</i>	U	"Single Crystal Silicon Supported Thin Film Micromirrors for Optical Applications", Z. Yao et al., Optical Engineering Society of Photo-Optical Instrumentation Engineers. Bellingham, WA, vol 36, No. 5, May 1, 1997, pp 1408-1413											
<i>OR</i>	V	"Vertical Comb Array MicroActuators", A. Selvakumar et al., Proceedings of the Workshop on Micro Electrical Mechanical Systems (MEMS), Amsterdam, New York, Jan 29-Feb 2, 1995, IEEE Vol. Workshop 8 Jan. 29, 1995, pp 43-48, ISBN 0-7803-2504-4											
EXAMINER <i>Chen Roger</i>										DATE CONSIDERED <i>1-10-03</i>			
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LIST OF PRIOR ART CITED BY APPLICANT (Use several sheets if necessary)										APPLICANT Behrang Behin et al.				
										FILING DATE 12/28/2000		GROUP 2894		
U.S. PATENT DOCUMENTS														
EXAMINER INITIAL		DOCUMENT NUMBER								DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<i>OR</i>	A	5	9	5	9	7	6	0	9/28/1999	Yamada et al.	359	224	7/28/1998	
	B													
	C													
FOREIGN PATENT DOCUMENTS														
		DOCUMENT NUMBER								DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
	D													
	E													
	F													
OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)														
<i>OR</i>	G	✓	"Fabrication of a 3D Differential-Capacitive Acceleration Sensor by UV-LIGA", W. Qu et al., Sensors and Actuators 77 (1999), pp 14-20, Elsevier Science, 0924-4247/99/\$											
<i>OR</i>	H	✓	"Integrating SCREAM Micromachined Devices with Integrated Circuits", K.A. Shaw, N.C MacDonald, IEEE MEMS '96, San Diego, California 1996, IEEE Publication 0-7803-2985-6/96, pp 44-48											
<i>OR</i>	I	✓	"An electrostatically excited 2D-Micro-Scanning-Mirror with an in-plane configuration of the driving electrodes", H. Schenk et al., MEMS 2000, 13 th Int. Micro Electro Mechanical Systems Conf, Miyazaki, Japan, p. 473-478 (2000).											
<i>OR</i>	J	✓	"Damping of Micro Electrostatic Torsion Mirror Caused by Air-Film Viscosity", N. Uchida et al.											
<i>OR</i>	K	✓	"Single Crystal Silicon (SCS) MicroMirror Arrays using Deep Silicon Etching and IR Alignment", C.S.B. Lee et al.											
<i>OR</i>	L	✓	U.S. Patent Application Serial No. 09/584,835 entitled "Staggered Torsional Electrostatic Comdrive and Method of Forming Same" by Robert A. Conant, Jocelyn T. Nee, Kam-Yin Lau and Richard S. Muller, filed May 31, 2000											
EXAMINER <i>John Rogers</i>										DATE CONSIDERED <i>1/16/03</i>				
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PTO-1449 U.S. DEPARTMENT OF COMMERCE		AGENT. DOCKET NO. ONX-105		SERIAL NO. 09/751,660			
LIST OF PRIOR ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Behrang Behin et al.			
				FILING DATE December 28, 2000		GROUP 2874	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.).							
<i>OK</i>	A	<input checked="" type="checkbox"/>	Fedder et al., "Multimode Digital Control of a Suspended Polysilicon Microstructure", IEEE Journal of Microelectromechanical Systems, Vol. 5, No. 4, December 1996, pp 283-297				
<i>OK</i>	B		Cheung et al., "Design, Fabrication, Position Sensing, and Control of an Electrostatically-driven Polysilicon Microactuator", IEEE Transaction of Magnetics, Vol. 32, No. 1, Jan. 1996, pp 122-128				
<i>OK</i>	C		Yun et al., "Surface Micromachined, Digitally Force-Balanced Accelerometer with Integrated CMOS Detection Circuitry", Tech. Digest IEEE Solid-State Sensor and Actuator Workshop, June 1992 pp 126-131				
EXAMINER <i>[Signature]</i>				DATE CONSIDERED <i>1/16/03</i>			
* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							